

## Supplementary materials

### Effect of interfacial SiO<sub>2</sub> layer thickness on the memory performances in HfAlO<sub>x</sub>-based ferroelectric tunnel junction for neuromorphic system

Yongjin Park,<sup>†a</sup> Jihyung Kim,<sup>†a</sup> Sunghun Kim<sup>a</sup>, Dahye Kim<sup>a</sup>, Wonbo Shim<sup>\*b</sup>, and Sungjun Kim<sup>\*a</sup>

<sup>a</sup> Division of Electronics and Electrical Engineering, Dongguk University, Seoul 04620, South Korea.

<sup>b</sup> Department of Electrical and Information Engineering, Seoul National University of Science and Technology, Seoul 01811, South Korea

E-mail: [wbslim@seoultech.ac.kr](mailto:wbslim@seoultech.ac.kr), [sungjun@dongguk.edu](mailto:sungjun@dongguk.edu)

<sup>†</sup>The authors contributed equally to this work.

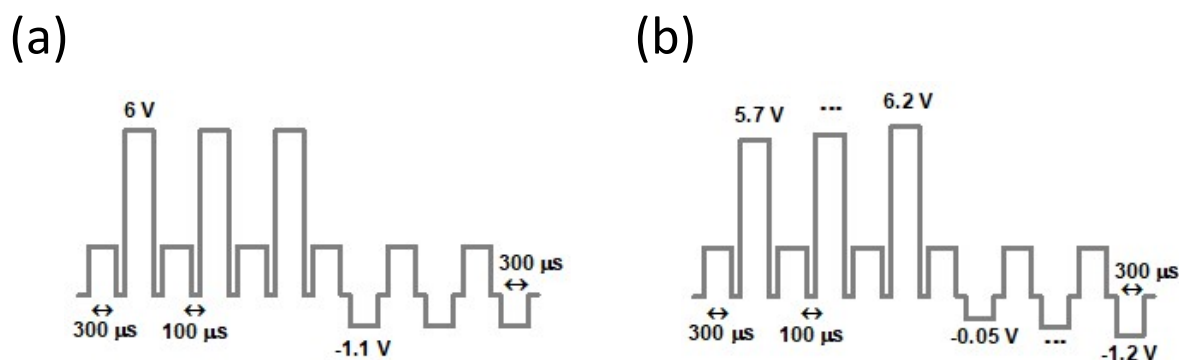


Fig. S1 (a) Identical and (b) incremental pulse schemes for potentiation and depression.

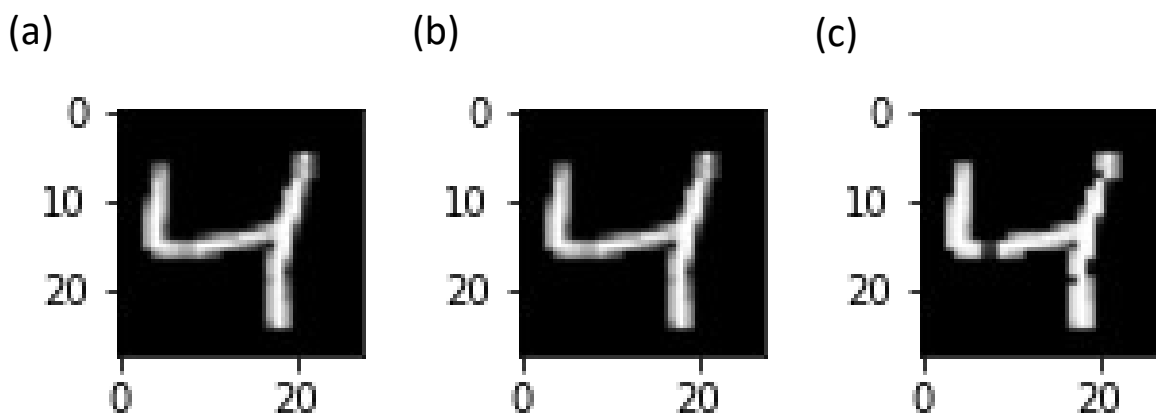


Fig. S2 Hand-written recognized MNIST numbers with respect to cycles of training of number 4 of (a) the ideal, (b) the incremental pulse scheme, and (c) the identical pulse scheme.